

- > S29: (01) "mu."
- > S30: (38) Backward citation search 2
- > S31: (2386918) thick\$4 thin\$4
- > S32: (9187572) thick\$4 thin\$4
- > S33: (2420112) conduct\$4
- > S34: (2529560) S12 S33
- > S35: (4880011) S14 with S34
- > S36: (772661) S35 with S32
- > S37: (101929 and S36
- > S38: (48) S21 and S36
- > S39: (10912) S36.clm.
- > S40: (9) S21 and S39
- > S41: (593) S18 adj2 S38
- > S42: (8) S41 and S39
- > S43: (4) S41 same S36
- > S44: (130198 same S36
- > S45: (2263424) thick\$4
- > S46: (1605001) S14 near6 S45
- > S47: (1076801) S34 near6 S45
- > S48: (77) S44 and S46
- > S49: (51) S48 and S47
- > S50: (231) S49 and S22
- > S51: (277201) S12 with S14
- > S52: (1011) S29 S50
- > S53: (4) S52 and S51

49 and 48

May 2005

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	Document Type	Title	Current Status	Review Date	S.C.P.	Image URL
1	<input type="checkbox"/>	Komoda; Ts US 659032 2003 H Field emission electron source	313/31	313/498	<input checked="" type="checkbox"/> <input type="checkbox"/>	
2	<input checked="" type="checkbox"/>	Busta; Hein US 6140646 2000 21 Direct view infrared MEMS structure	250/38	250/238.1	<input checked="" type="checkbox"/> <input type="checkbox"/>	US 614064
3	<input type="checkbox"/>	Bartha; Joh US 5116482 1992 H Method of producing micromechanical	210/2	210/71	<input checked="" type="checkbox"/> <input type="checkbox"/>	
4	<input checked="" type="checkbox"/>	Bernstein; J US 4705652 1987 1 H Carbon film oxidation for free-standing	264/29	264/72	<input checked="" type="checkbox"/> <input type="checkbox"/>	

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